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Energy Gap Evaluation in Microcrystalline m-HfO₂ Powder

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Abstract. In this paper optical properties of microcrystalline HfO₂ powder are investigated. X-ray diffraction and Raman spectroscopy were used to determine that the studied samples are in monoclinic phase. Based on the analysis of the diffuse reflectance spectra and applying Kubelka-Munk formalism we evaluated the indirect bandgap value $E_g = 5.34 \pm 0.05$ eV. The calculated value is in agreement with independent data for HfO₂ thin films synthesized by various methods. The paper is based on the materials of the report presented at the first Russian scientific conference with the participation of the international community "YENISEI PHOTONICS – 2020".

Keywords: hafnium dioxide, diffuse reflectance, absorption edge

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Introduction

Hafnium dioxide meets great interest of modern condensed matter physics as a wide-gap high-k material with superior thermal and chemical stability. Along with the other IVB metal oxides (ZrO₂, TiO₂) HfO₂ is considered to be a promising solid-state medium for creation of the

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non-volatile memory cells because of its physical properties and favorable valence and conduction band alignments [1–5]. Due to wide energy gap and high refractive index hafnia is used as optical coatings [6]. As downscaling of field effect transistors has become difficult, HfO₂ could also be a candidate to replace SiO₂ as gate dielectric [7]. However, a deep understanding of the fundamental features in electronic structure and of the regularities in the functional characteristics formation is required to solve problems and to further develop the application principles of hafnium dioxide in opto- and nanoelectronic devices [2]. This work is devoted to the study of the structural and optical properties of nominally pure HfO₂ powder based on the sample characterization methods and analysis of diffuse reflectance spectra.

1. Experimental

In this paper the commercial hafnia powder of the HFO-1 grade (TU 48-4-201-72) was investigated. The purity of HfO₂ powder is 99.9%, and the concentration of ZrO₂ does not exceed 0.1%.

HfO₂ powder was characterized by AurigaCrossBeam (Carl Zeiss) scanning electron-ion microscope (SEM) with an accelerating voltage of 1 kV, coupled with an EDS device X-max 80 (Oxford Instruments) for analysis of chemical composition. The structural properties were studied by X-ray diffraction (XRD) measurements by X’Pert PRO MPD PANalytical diffractometer with CuK α radiation operating at 40 kV and 30 mA in the 2θ range from 10° to 90°, step size 0.05°.

Raman spectra were measured using Renishaw U1000 spectrometer under excitation by Cobolt Samba solid-state laser with a wavelength of 532 nm (5 mW power) and were recorded in the extended mode within the range of 50–850 cm⁻¹ with spectral resolution of 1 cm⁻¹. The measurement of the diffuse reflectance spectra was performed using double beam SHIMADZU UV-2450 spectrophotometer and integrating sphere attachment ISR-2200 in range of 220–850 nm at room temperature and with barium sulfate used as the white reference plate.

2. Results

Fig.1 shows SEM-image of the investigated powder. According to the obtained images, the size of the particles is in range 1–40 μm . Analysis of the chemical composition revealed the presence of 83.8 ± 0.5 wt.% hafnium and 16.2 ± 0.5 wt.% oxygen in the sample. The obtained ratio is close to stoichiometric one. No impurities with noticeable concentration were found in the investigated powder.

XRD pattern of the HfO₂ powder is shown in Fig. 2a. The peaks correspond to m-HfO₂ – monoclinic, baddeleyite structure, group P2₁/c. This conclusion was confirmed by the analysis of the Raman spectrum (Fig. 2b). 17 peaks with the most intensive mode near 500 cm⁻¹ is a characteristic set for m-HfO₂. In Fig. 2b the corresponding phonon modes are presented next to the peaks. It is noteworthy that the maximum near 135 cm⁻¹ is the superposition of two active modes [8].

In Fig. 2c the diffuse reflectance spectrum is shown. A sharp decrease is observed for $\lambda < 250$ nm. Also, for $\lambda = 240$ nm local maximum is present and the reflectance $R > 95\%$ in range of $\lambda > 400$ nm.

3. Discussion

The measured diffuse reflectance spectrum was transformed into spectral dependence for optical absorption coefficient α using Kubelka-Munk function $F(R)$ (1) [5,9]:

$$\alpha \sim F(R) = \frac{(1 - R)^2}{2R}. \quad (1)$$

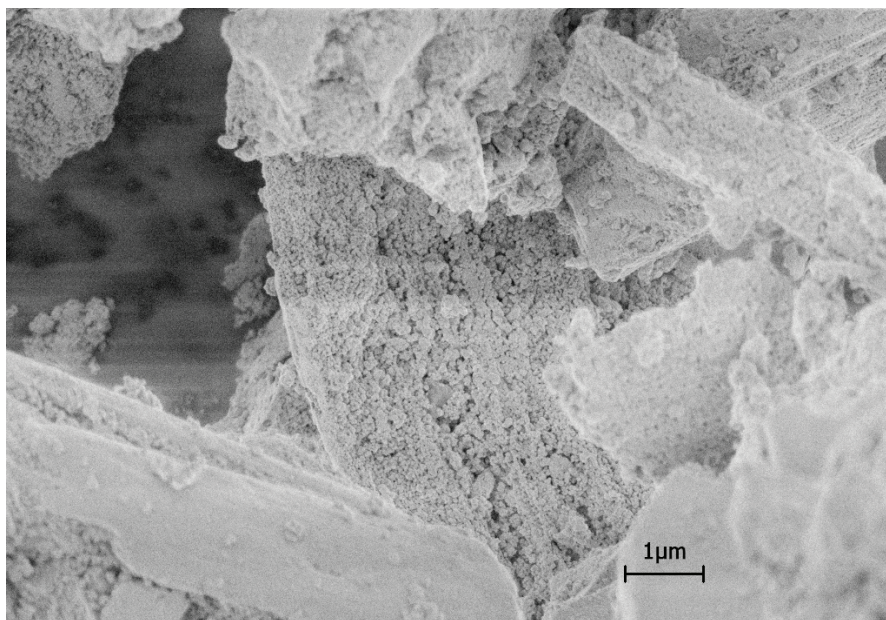


Fig. 1. SEM micrograph of HfO₂ powder under study

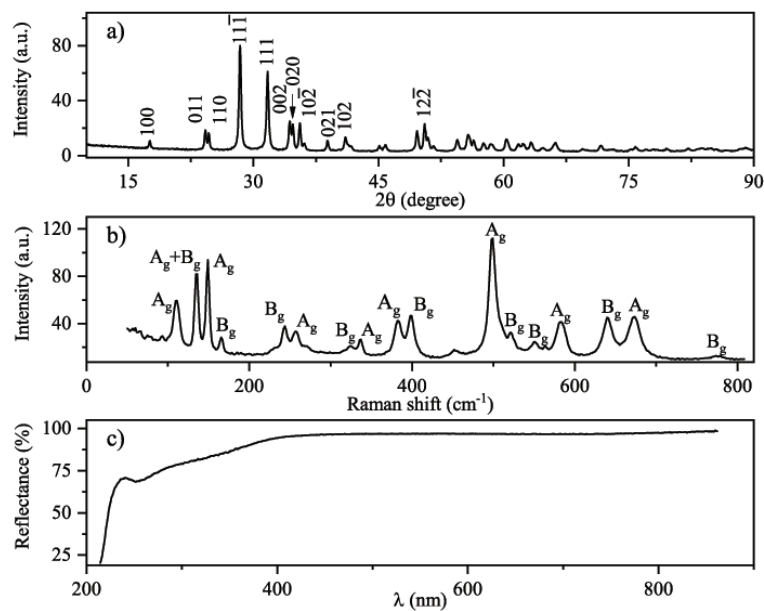


Fig. 2. Characterization of the investigated HfO₂ powder: a) XRD pattern, b) Raman-shift data, c) Diffuse reflectance spectrum

The obtained data is presented in Fig. 3. For the energy of incident photons $h\nu > 5.25$ eV the sharp increase due to optical transitions near intrinsic absorption edge is noted. A small broad band is observed in the energy range of 4.6–5.1 eV and an extended shoulder is present up to 3 eV. Considering the data on the absence of impurities in the studied powder we can conclude that

the indicated spectral features have intrinsic origin in m-HfO₂ [10]. It is known that intrinsic absorption edge in m-HfO₂ is caused by indirect band-to-band transitions [7] and in this case should be applied (2) [11]:

$$\alpha h\nu = A(h\nu - E_g)^2, \quad (2)$$

where A is constant, $eV^{-1} \cdot cm^{-1}$.

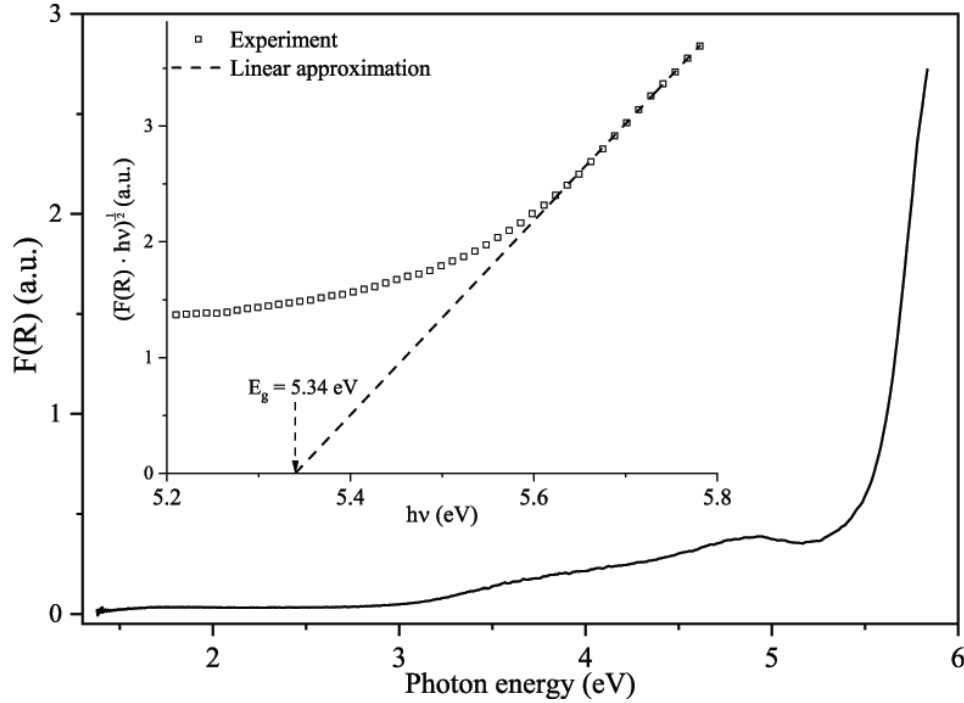


Fig. 3. Kubelka-Munk function, calculated for the diffuse reflectance spectrum. The inset shows optical bandgap evaluation

Bandgap value was evaluated using Tauc plot in coordinates $(F(R) \cdot h\nu)^{\frac{1}{2}}$. Linear part of the dependence was extrapolated in order to calculate the energy gap value $E_g = 5.34 \pm 0.05$ eV. It should be noted that this estimation was made up to emitted phonon energy $\hbar\omega$. Area of the intrinsic absorption edge $h\nu + \hbar\omega > E_g$ which corresponds to indirect transitions with absorption of vibrational modes is distorted by defect-induced processes in the band area of 4.9 eV. Nevertheless, the obtained E_g value is in agreement with other independent data. In particular, for HfO₂ thin films of produced by ion beam sputtering deposition method $E_g = 5.4 \pm 0.05$ eV [6]. For the films synthesized using atomic-layer deposition technique energy gap value is 5.55 eV [7].

Conclusion

In this paper structural and optical properties of pure HfO₂ powder were studied. XRD and Raman spectroscopy methods were used to identify that the sample is stabilized in monoclinic phase. SEM was used to determine that the size of the particles is in range 1–40 μ m, impurities are absent. Based on the analysis of the diffuse reflectance spectra in the region of the intrinsic absorption edge at $\lambda < 250$ nm, using the Kubelka-Munk function and the Tauc plot for indirect allowed transitions, the energy gap was evaluated as $E_g = 5.34 \pm 0.05$ eV. The results obtained are consistent with independent data for thin HfO₂ films.

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Оценка ширины запрещенной зоны в микрокристаллическом порошке m-HfO₂

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Аннотация. В работе изучены оптические свойства микрокристаллического порошка диоксида гафния. Методами рентгеновской дифракции и рамановской спектроскопии установлено, что исследуемые образцы обладают моноклинной кристаллической решёткой. На основе анализа спектров диффузного отражения и применения формализма Кубелки-Мунка выполнена оценка ширины не прямой запрещённой зоны $E_g = 5.34 \pm 0.05$ эВ. Полученная величина согласуется с независимыми данными для пленок HfO₂, синтезированных различными методами. Статья подготовлена по материалам доклада на Первой Всероссийской научной конференции с международным участием «ЕНИСЕЙСКАЯ ФОТНИКА — 2020.»

Ключевые слова: диоксид гафния, диффузное отражение, край поглощения.